

Thin Film Materials Characterization Services

NANO3D provides physicochemical characterization services of the metal foils and films deposited on different substrates.

Thermal Properties:

• Specific heat capacity

Differential Scanning Calorimetry (SDT Q600) analyzes specific heat capacity over the temperature range from ambient to 1500 °C.

• Linear thermal expansion Testing linear thermal expansion of the metal alloys using technique based on bending of bonded layers due to the thermal stress.

• Thermal conductivity Testing the planar thermal conductivity of the thin films (down to 5 μ m).

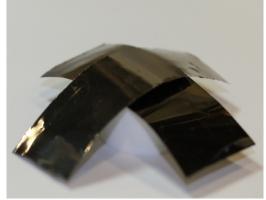
Mechanical Properties:

Internal stress and adhesion

The internal stress has been studied using the bent strip technique. Stud pull testing is used to measure the adhesion.

• Elastic and plastic characteristics

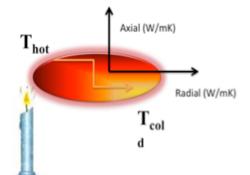
The tension test utilizing Instron technique evaluates Young's modulus, yield strength, tensile strength and ductility of the thin films.



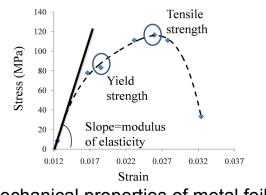
Controlled expansion alloy films for shadow masks, bimetallic actuators



Linear thermal expansion



Planar (radial) thermal conductivity



Mechanical properties of metal foils



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Surface morphology:

• Thickness, uniformity, roughness The surface roughness of the films controlled by optical profilometer and Atomic Force Microscopy (AFM) for areas which vary from several nanometers up to 500 µm.

Alloy composition:

• Metal alloy composition

The composition of the alloy by weight percentage is studied via UV-VIS spectroscopy.

Elemental composition

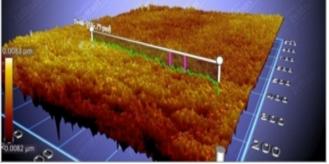
The elemental composition of the surface of the films is measured by Scanning Electron Microscopy coupled with Energy Dispersive X-ray Spectroscopy (SEM/EDX). The resolution of the SEM is 3 - 5 nm, and the spectral resolution of EDX is 2%.

Thin film cross-sections are prepared by Focus Ion Beam (FIB) and analyzed by Transmission Electron Microscopy (TEM). Accelerating voltages range from 20-120 kV, providing a point resolution of 2.7 Å. Electron diffraction patterns can be obtained from the crystals as small as 1 nm.

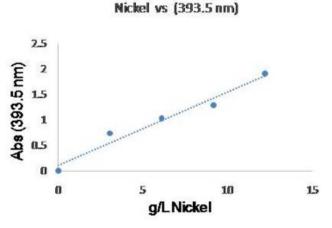
• Impurities

Quantitative secondary ion mass (SIMS) spectroscopy analysis evaluates the distribution of impurities dopants in metal films and in semiconductors. It provides elemental depth profiles over depth ranges from a few angstroms (Å) to tens of microns.

Time-Of-FlightSIMSallowsmeasurementsofverylowconcentrations of impurities & dopantswith detection limit of 1×10^{16} atoms/ccand can be readily quantified to within±20% of that ultra-low concentration.



Surface morphology of the metal foils by optical profilometer



Calibration curve of the dissolved nickel based on the UV-visible spectra

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